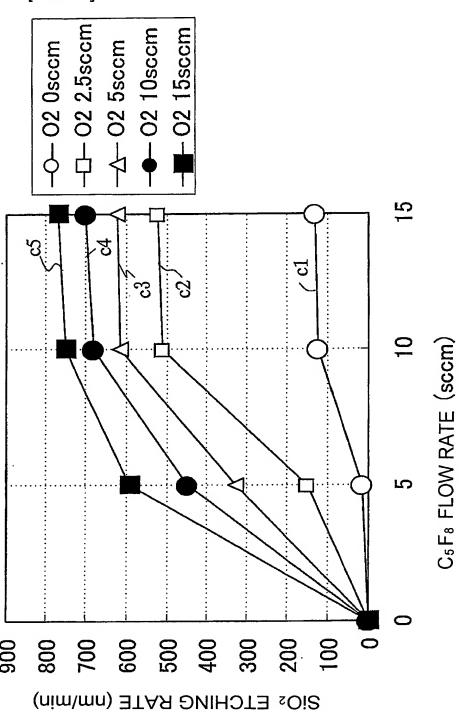
Title: METHOD OF MANUFACTURING A SEMICONDUCTOR DEVICE AND METHOD OF ETCHING AN INSULATING FILM

Inventor(s): Tadahiro OHMI, et al DOCKET NO.: 039262-0156

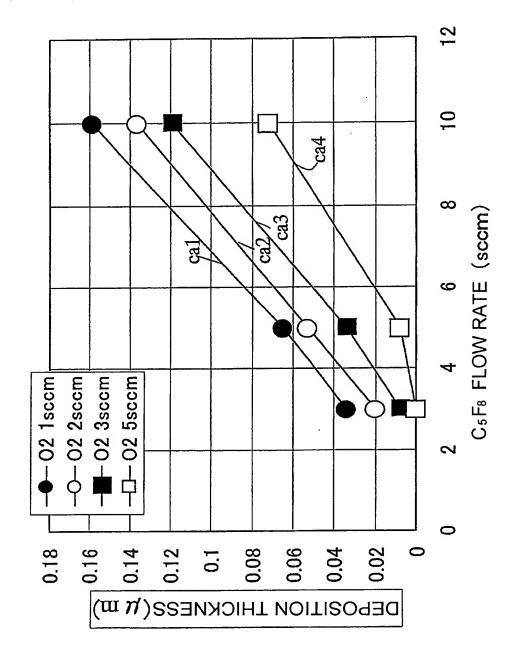
[FIG. 1]



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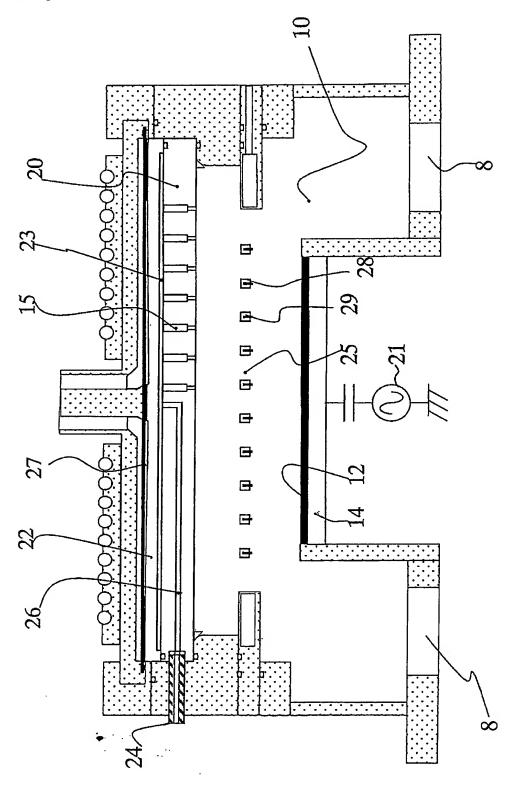
[FIG. 2]



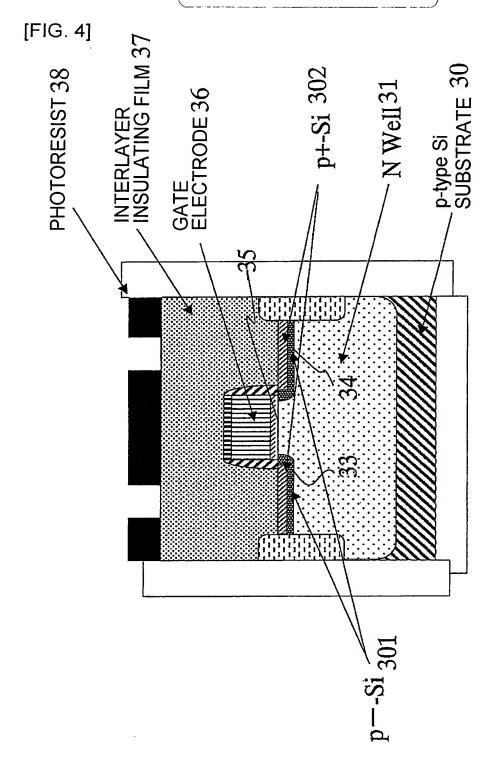
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[FIG. 3]

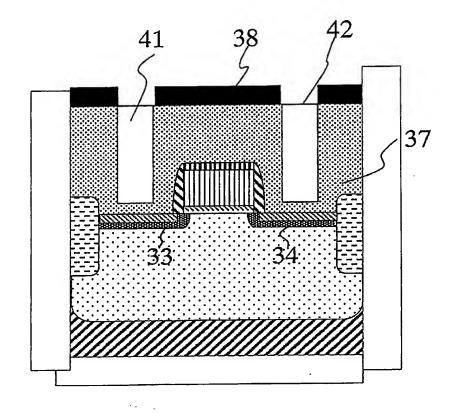


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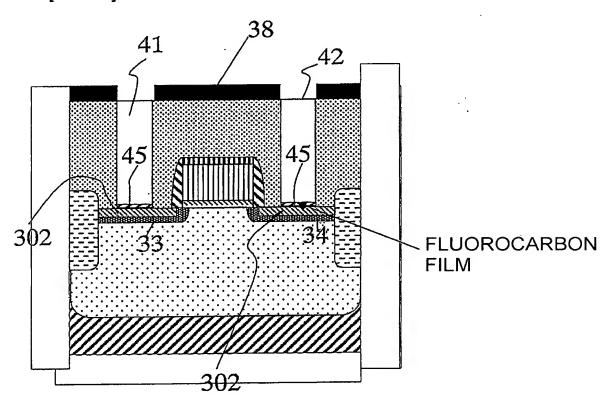


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[FIG. 5]



[FIG. 6]



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[FIG. 7]

